

Most Frequently Occurring Classifications of Patents Returned
From A Search of 09882465 on May 06, 2003

Original Classifications

22 250/306
10 73/105
2 250/234
2 250/307
2 250/442.11
2 359/372

Cross-Reference Classifications

11 250/307
10 250/306
9 250/442.11
3 250/440.11
2 73/105
2 250/234
2 310/331
2 359/212
2 359/224
2 359/368

Combined Classifications

32 250/306
13 250/307
12 73/105
11 250/442.11
4 250/234
3 250/440.11
3 359/372
2 250/216
2 310/331
2 359/198
2 359/202
2 359/212
2 359/224
2 359/368

Titles of Most Frequently Occurring Classifications of Patents Returned
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32	250/306	(22 OR, 10 XR)
	Class 250 :	RADIANT ENERGY
	250/306	INSPECTION OF SOLIDS OR LIQUIDS BY CHARGED PARTICLES
13	250/307	(2 OR, 11 XR)
	Class 250 :	RADIANT ENERGY
	250/306	INSPECTION OF SOLIDS OR LIQUIDS BY CHARGED PARTICLES
	250/307	.Methods
12	73/105	(10 OR, 2 XR)
	Class 073 :	MEASURING AND TESTING
	73/104	SURFACE AND CUTTING EDGE TESTING
	73/105	.Roughness
11	250/442.11	(2 OR, 9 XR)
	Class 250 :	RADIANT ENERGY
	250/306	INSPECTION OF SOLIDS OR LIQUIDS BY CHARGED PARTICLES
	250/440.11	.Analyte supports
	250/442.11	..With object moving or positioning means
4	250/234	(2 OR, 2 XR)
	Class 250 :	RADIANT ENERGY
	250/200	PHOTOCELLS; CIRCUITS AND APPARATUS
	250/216	.Optical or pre-photocell system
	250/234	..Means for moving optical system
3	250/440.11	(0 OR, 3 XR)
	Class 250 :	RADIANT ENERGY
	250/306	INSPECTION OF SOLIDS OR LIQUIDS BY CHARGED PARTICLES
	250/440.11	.Analyte supports
3	359/372	(2 OR, 1 XR)
	Class 359 :	OPTICS: SYSTEMS
	359/362	COMPOUND LENS SYSTEM
	359/368	.Microscope
	359/372	..With plural optical axes
2	250/216	(1 OR, 1 XR)
	Class 250 :	RADIANT ENERGY
	250/200	PHOTOCELLS; CIRCUITS AND APPARATUS
	250/216	.Optical or pre-photocell system
2	310/331	(0 OR, 2 XR)
	Class 310 :	ELECTRICAL GENERATOR OR MOTOR STRUCTURE
	310/300	NON-DYNAMOELECTRIC
	310/311	.Piezoelectric elements and devices
	310/328	..With mechanical energy coupling means
	310/330	...Bending type
	310/331Plural elements
2	359/198	(1 OR, 1 XR)
	Class 359 :	OPTICS: SYSTEMS

359/196 DEFLECTION USING A MOVING ELEMENT OR MEDIUM
 (OFFSETTING OR CHANGING AT LEAST A PORTION
 OF THE BEAM)
 359/197 .Using a periodically moving element (periodic
 change of optically reflecting, refracting
 or diffracting element)
 359/198 ..Particular mount or driver for element

2 359/202 (1 OR, 1 XR)
 Class 359 : OPTICS: SYSTEMS
 359/196 DEFLECTION USING A MOVING ELEMENT OR MEDIUM
 (OFFSETTING OR CHANGING AT LEAST A PORTION
 OF THE BEAM)
 359/197 .Using a periodically moving element (periodic
 change of optically reflecting, refracting
 or diffracting element)
 359/201 ..Plural moving scanning elements
 359/202 ...X-Y scanner

2 359/212 (0 OR, 2 XR)
 Class 359 : OPTICS: SYSTEMS
 359/196 DEFLECTION USING A MOVING ELEMENT OR MEDIUM
 (OFFSETTING OR CHANGING AT LEAST A PORTION
 OF THE BEAM)
 359/197 .Using a periodically moving element (periodic
 change of optically reflecting, refracting
 or diffracting element)
 359/212 ..Including reflective type moving element

2 359/224 (0 OR, 2 XR)
 Class 359 : OPTICS: SYSTEMS
 359/196 DEFLECTION USING A MOVING ELEMENT OR MEDIUM
 (OFFSETTING OR CHANGING AT LEAST A PORTION
 OF THE BEAM)
 359/223 .By moving a reflective element
 359/224 ..Reflective element moved by deformable
 support

2 359/368 (0 OR, 2 XR)
 Class 359 : OPTICS: SYSTEMS
 359/362 COMPOUND LENS SYSTEM
 359/368 .Microscope